

Figure 1

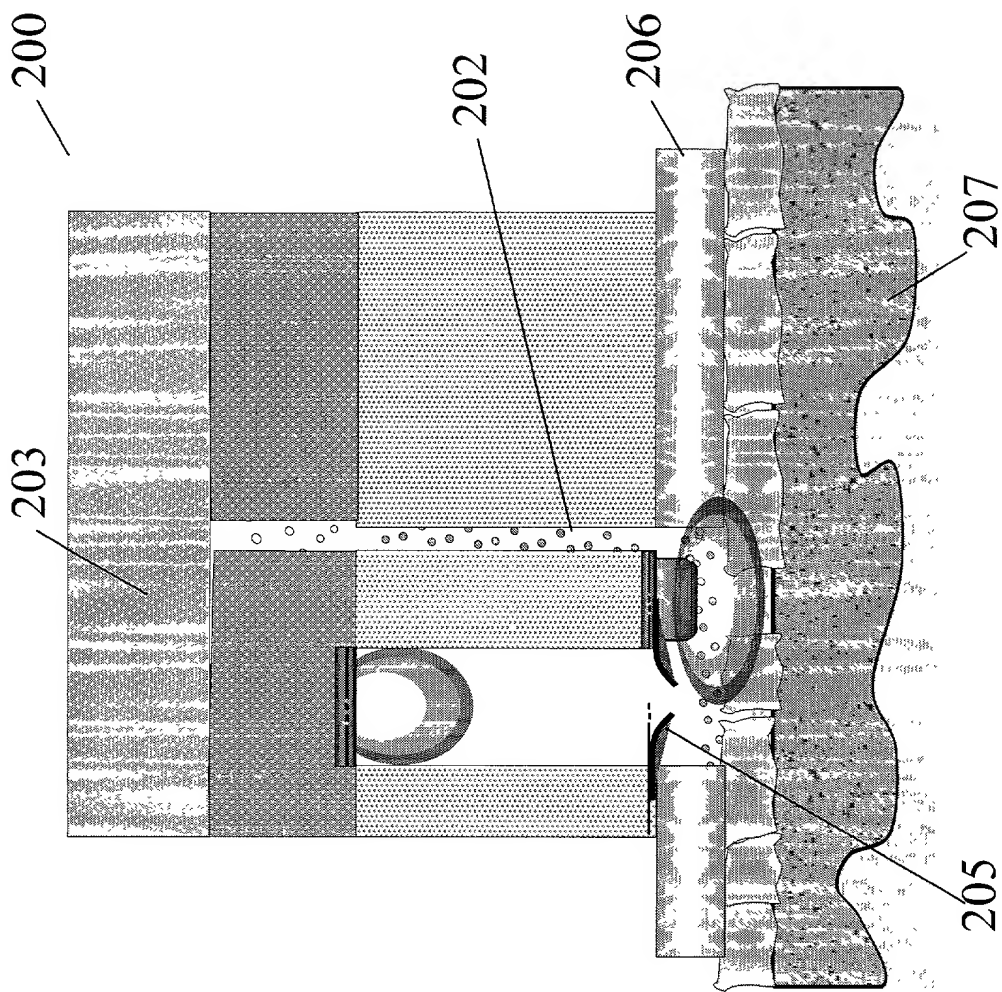


Figure 2

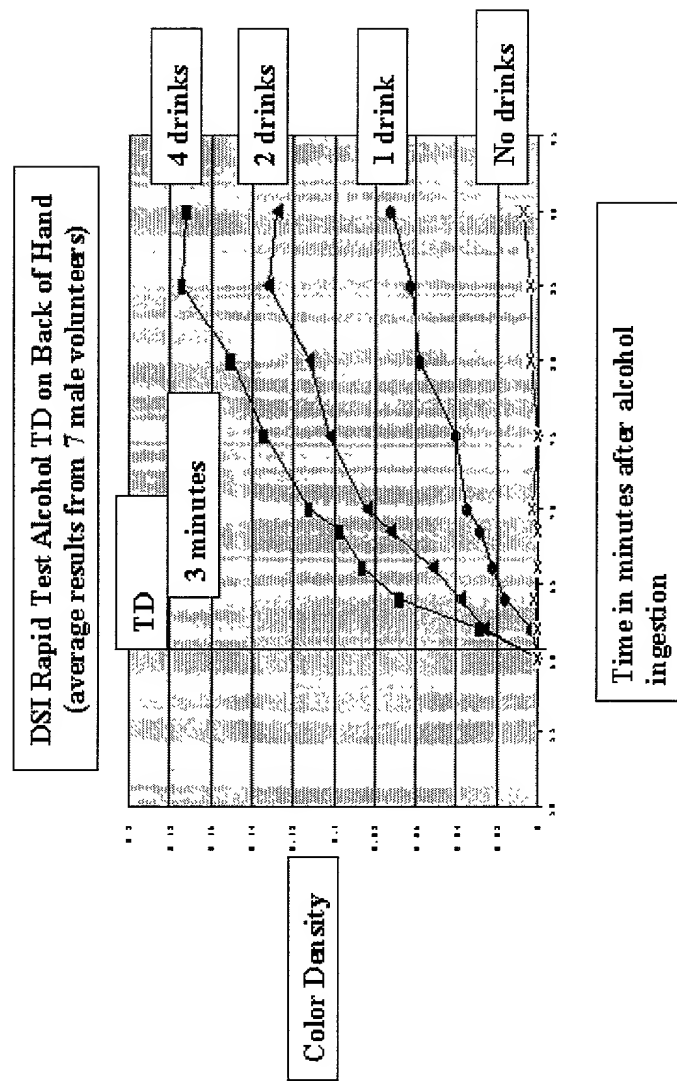


Figure 3

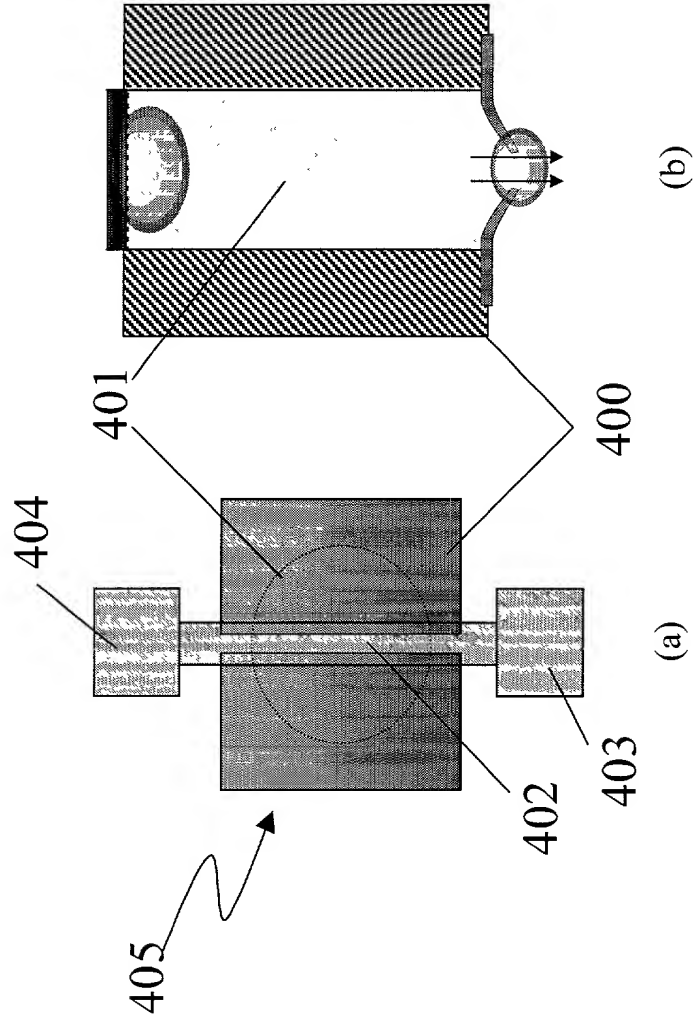


Figure 4

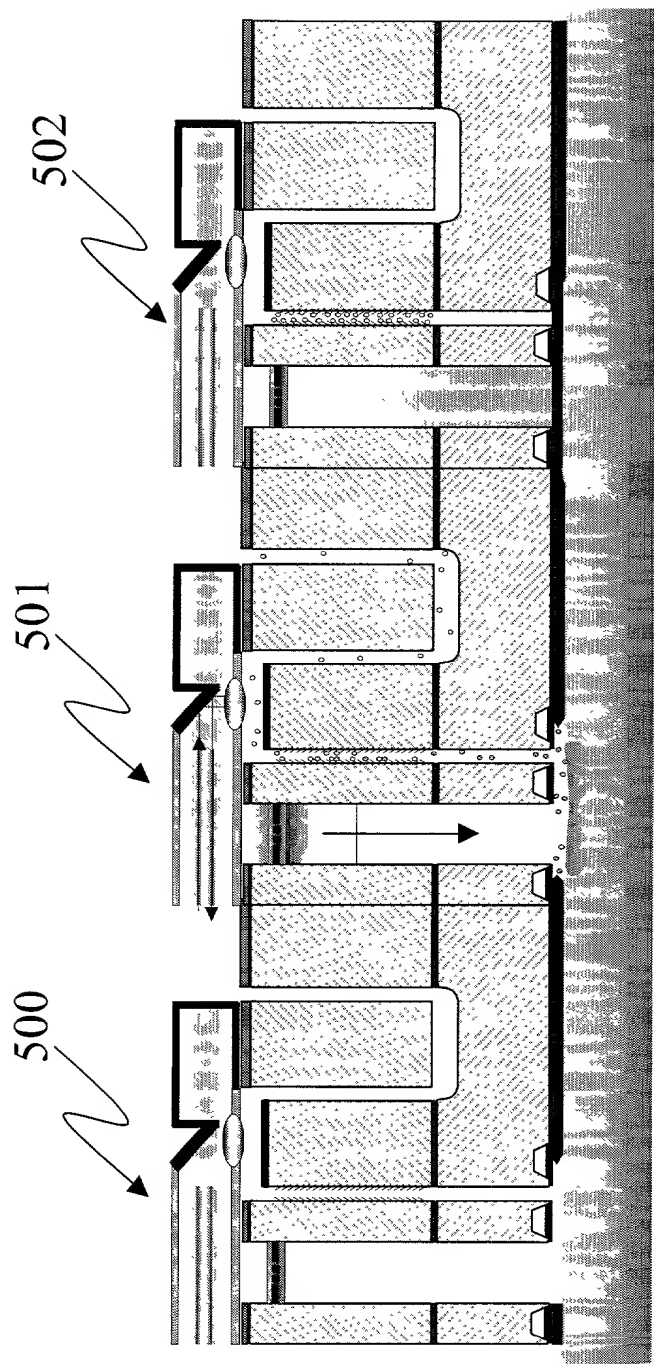


Figure 5

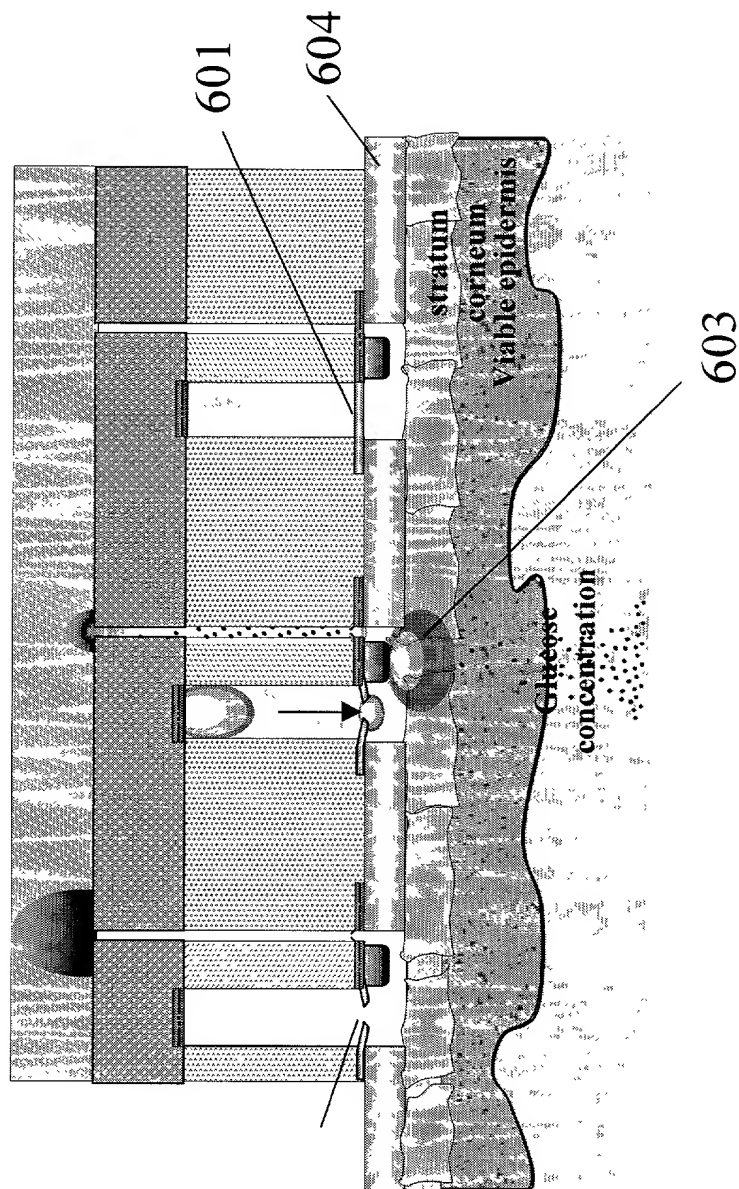


Figure 6

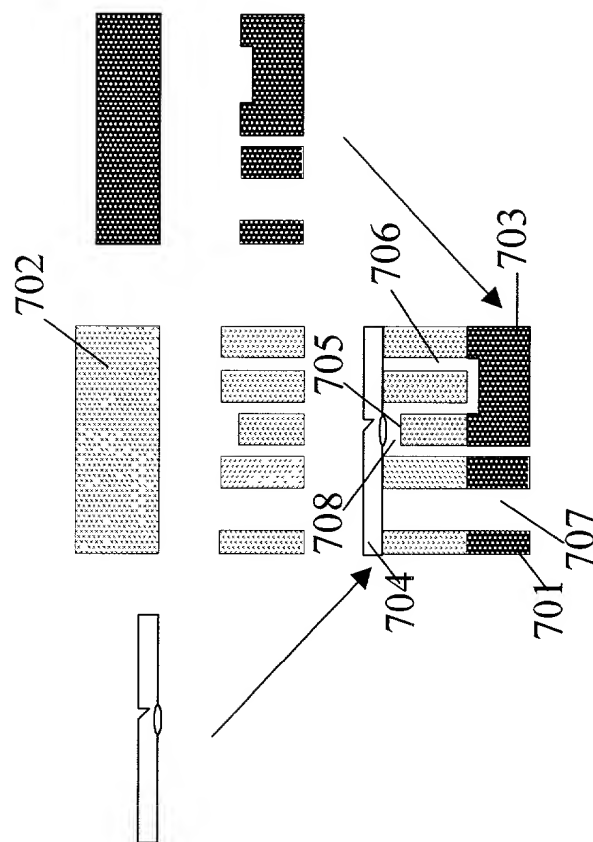


Figure 7

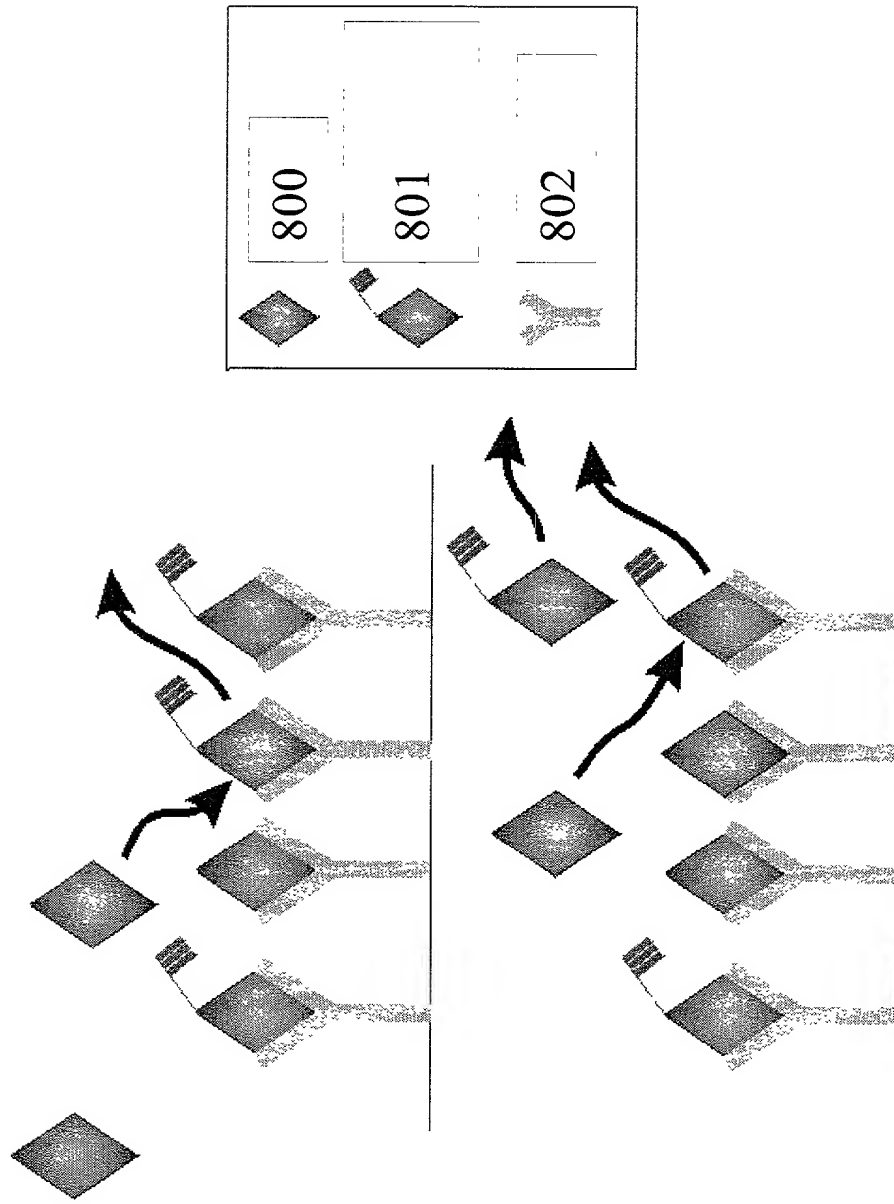


Figure 8

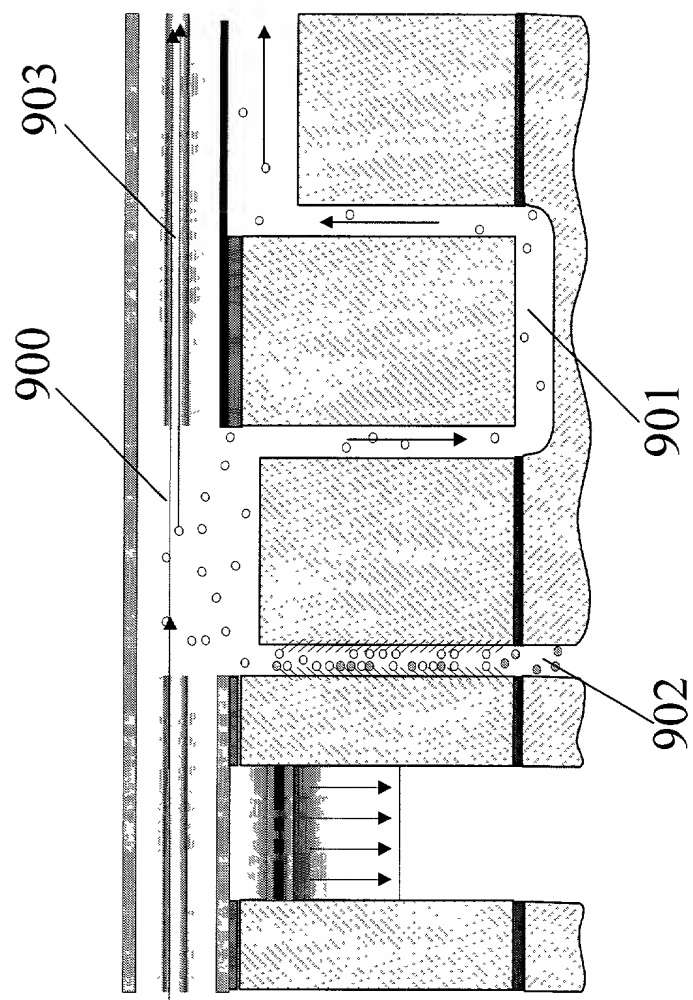


Figure 9

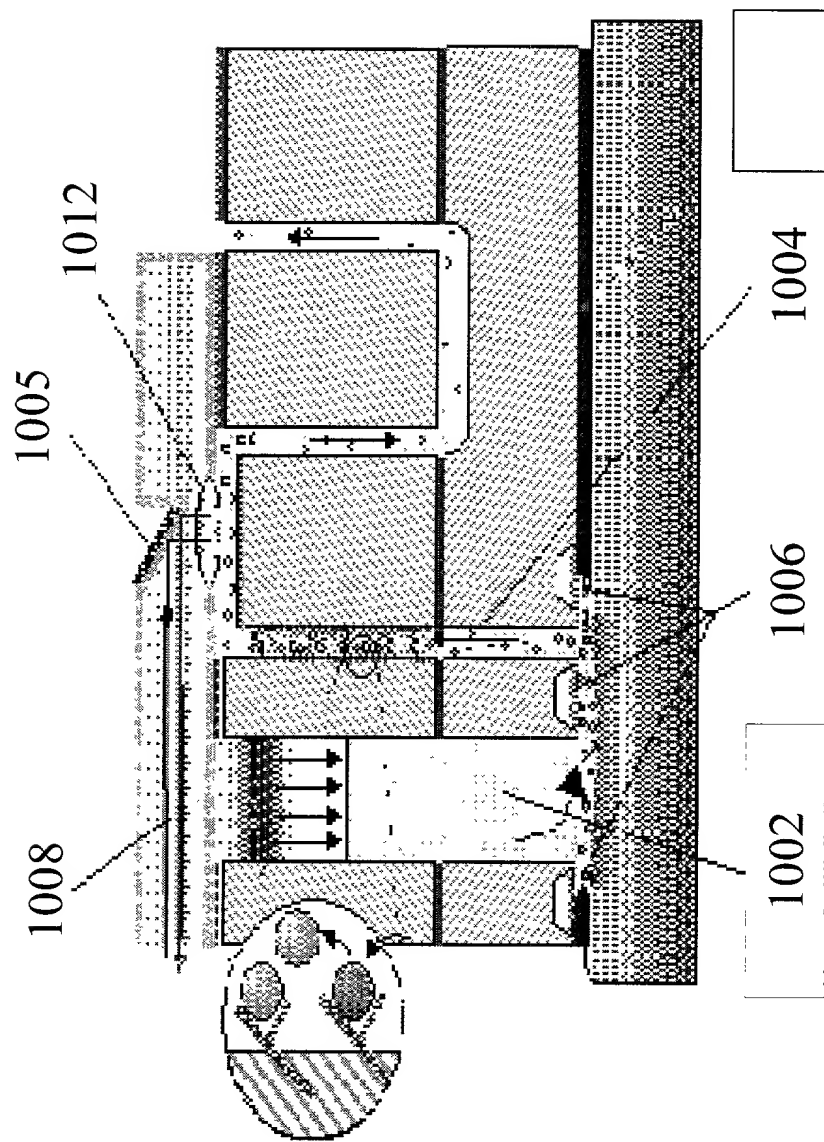


Figure 10

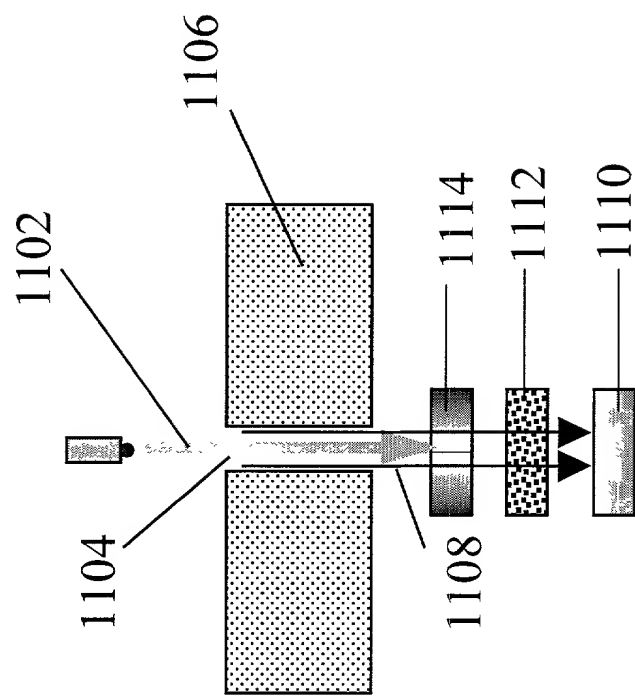


Figure 11

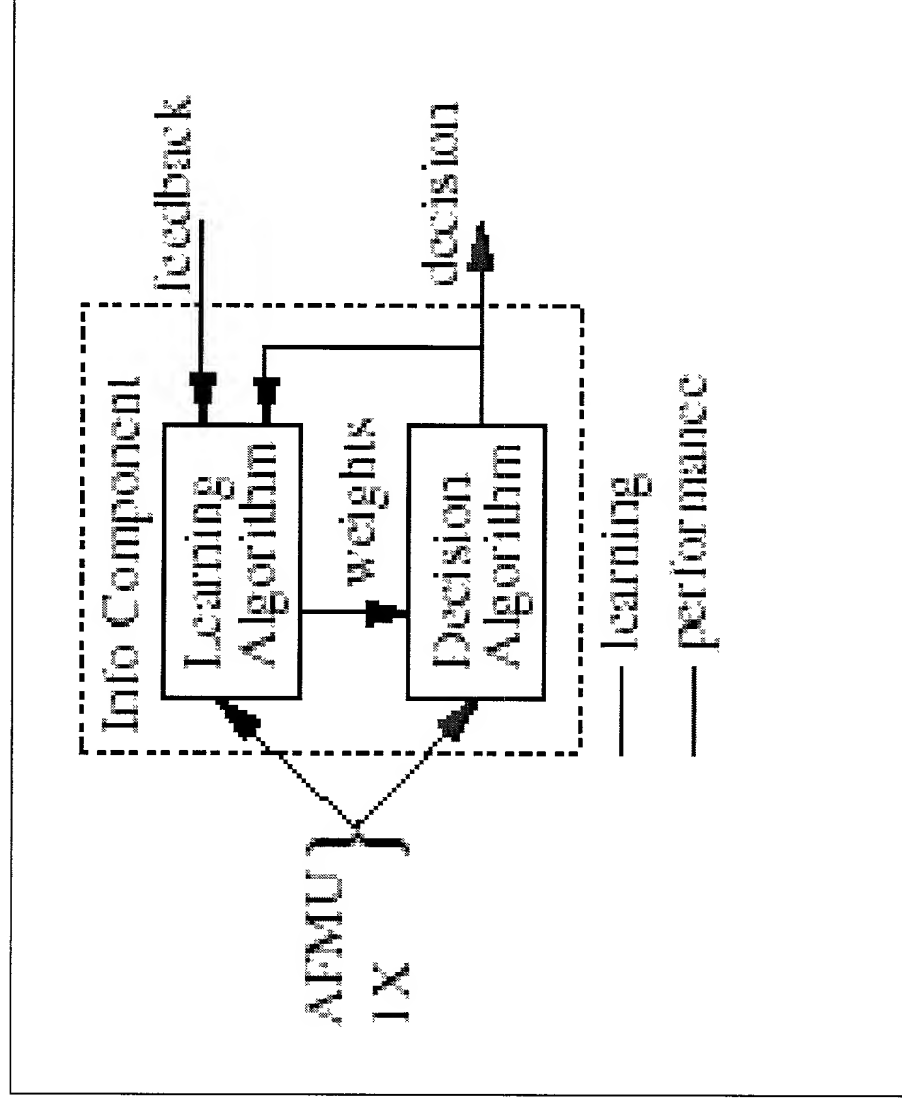


Figure 12

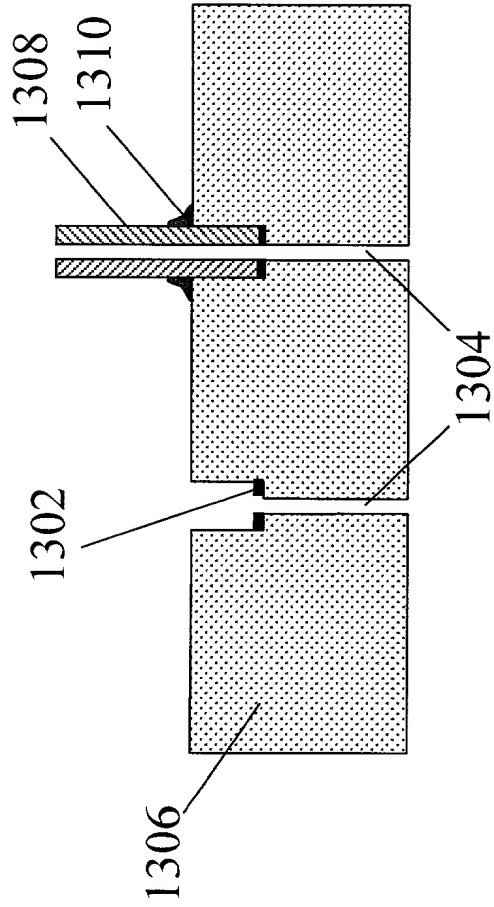


Figure 13

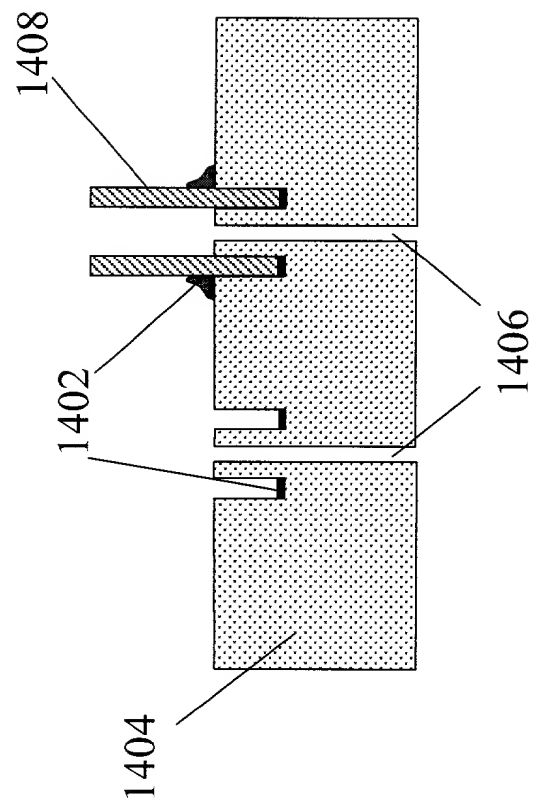


Figure 14

FIG. 15 is a schematic diagram of a device 1500, which includes a substrate 1502, a laser light source 1508, a fluorescent light source 1510, and a light path 1504.

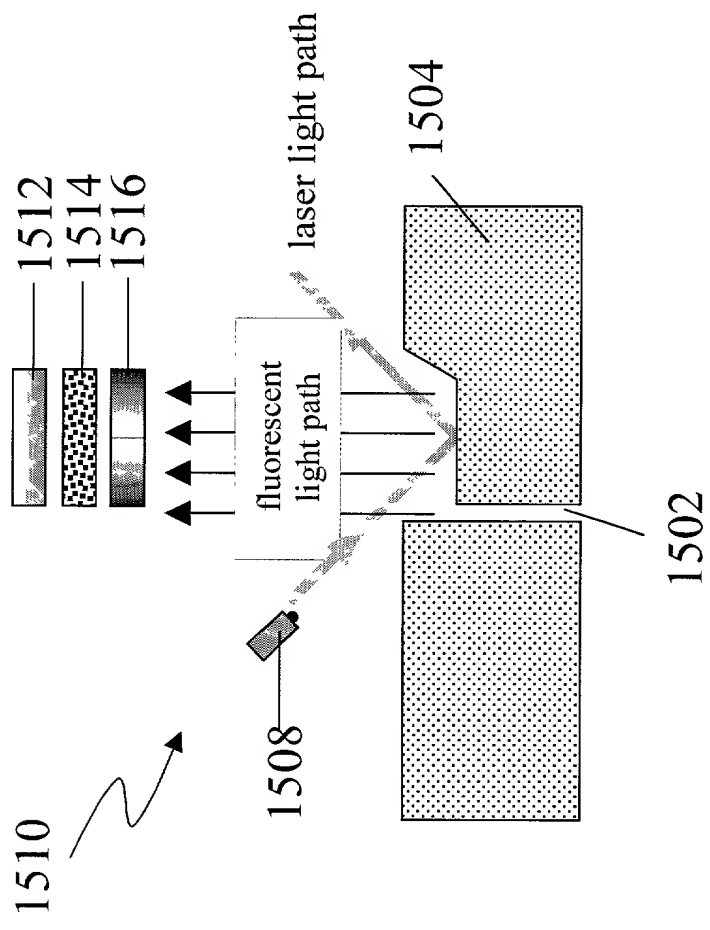


Figure 15

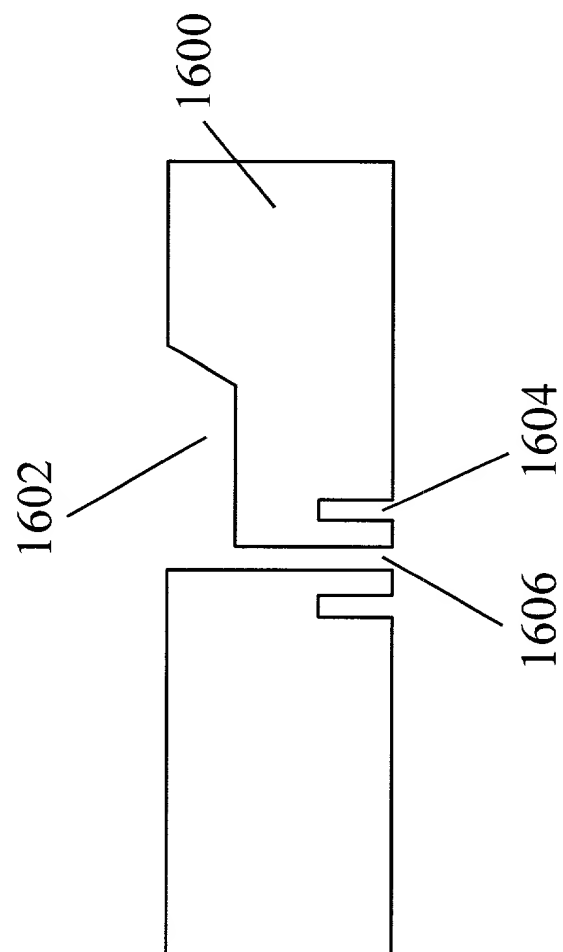


Figure 16

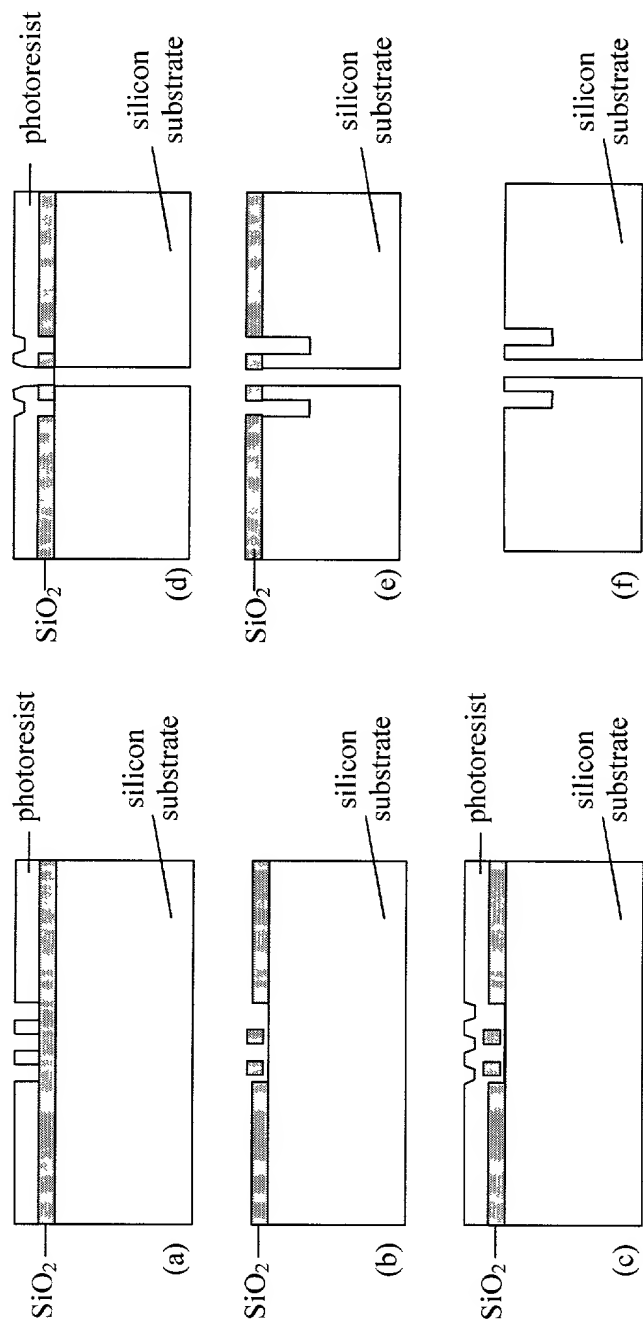


Figure 17

Figure 18 shows three cross-sectional views of a semiconductor device structure, illustrating the formation of a trench and the subsequent deposition of a dielectric layer.

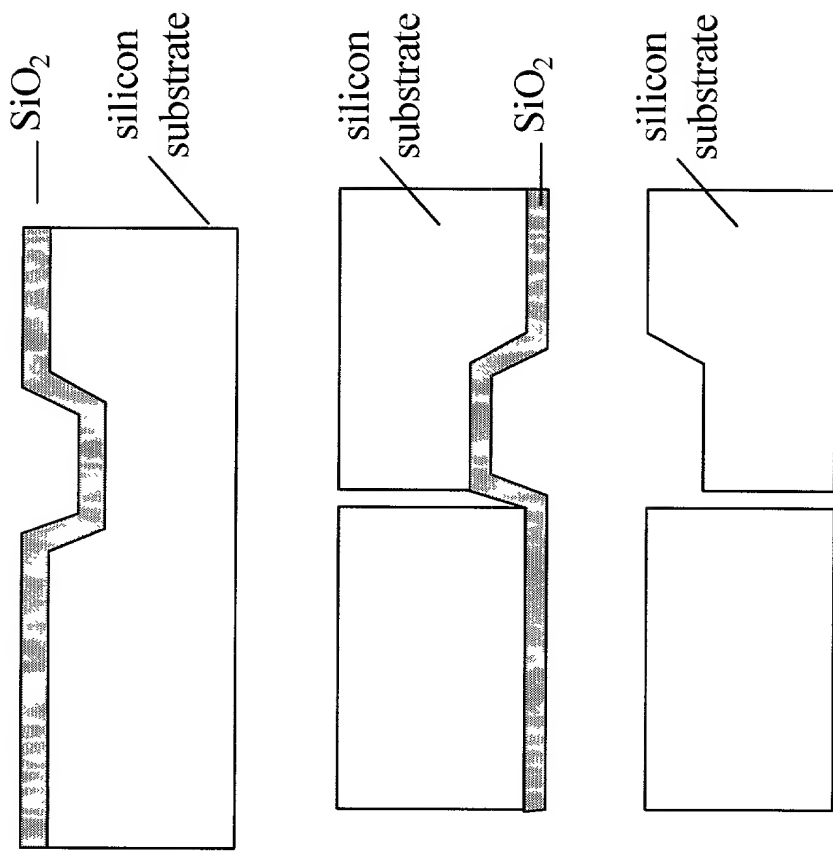


Figure 18

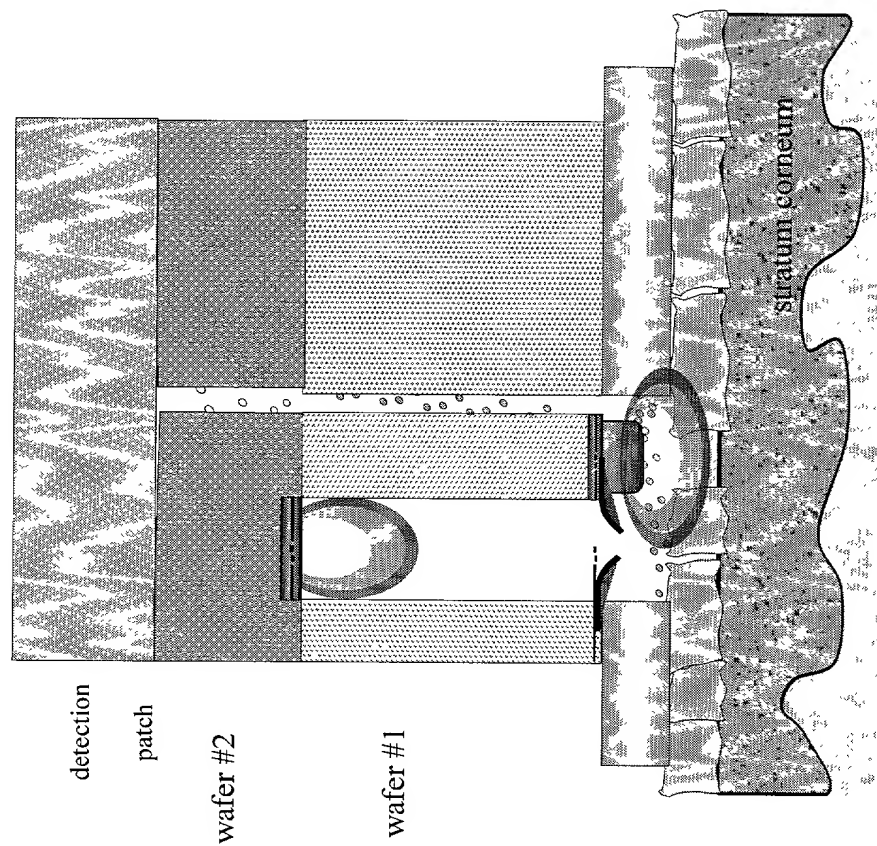
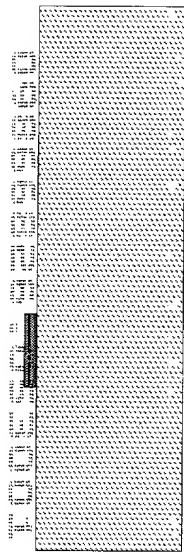


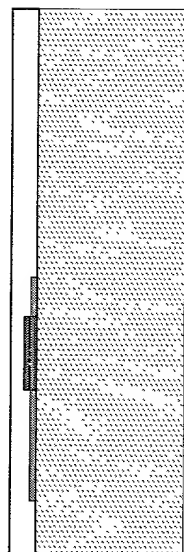
Figure 20



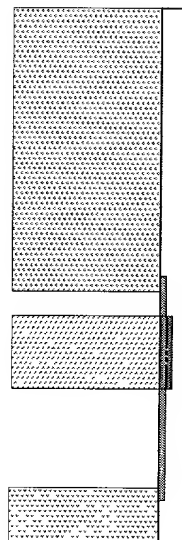
(a)



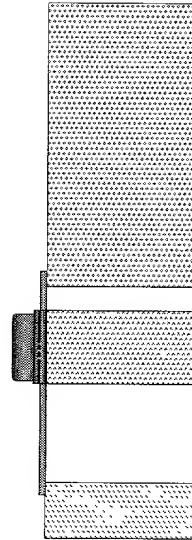
(b)



(c)



(d)



(e)

Figure 21

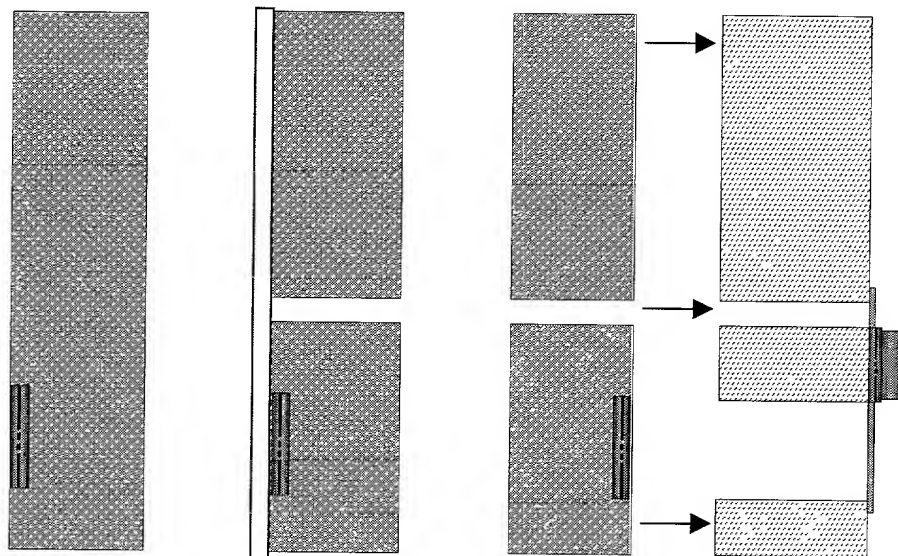


Figure 22

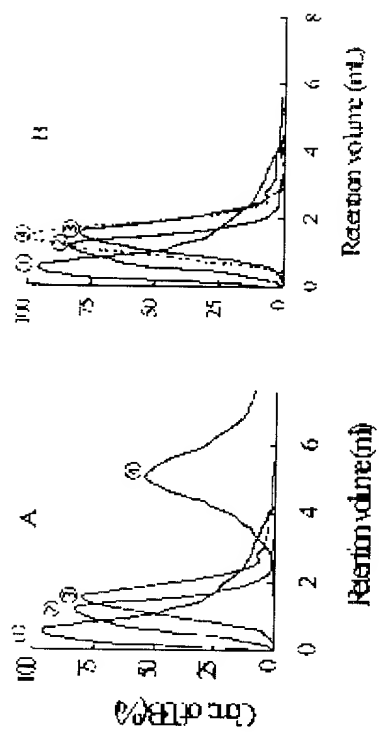


Figure 23

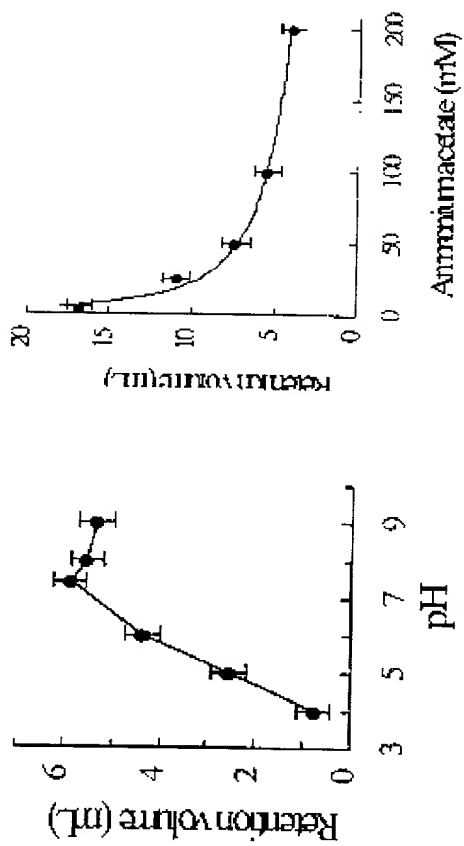


Fig. 3

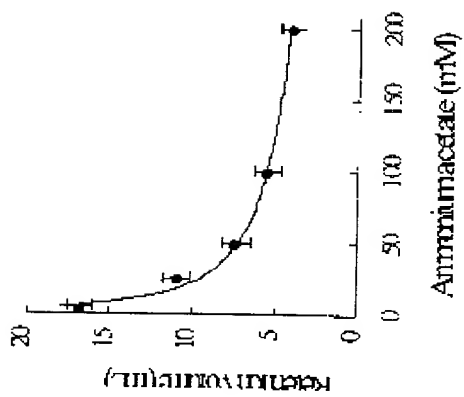


Fig. 4

Figure 24